

18-09-22

\* Conductivity and mobility are both temperature dependent.

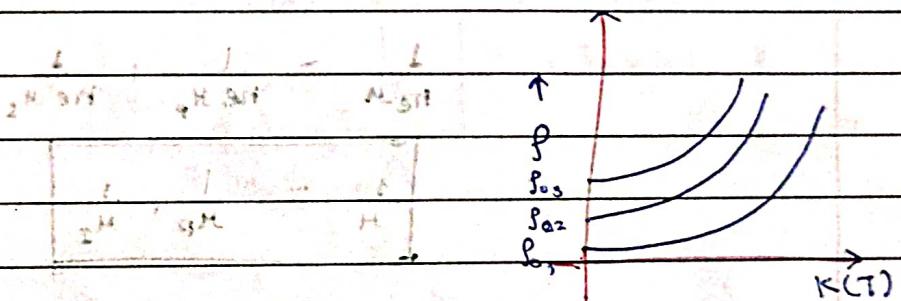
- Low temperature scattering mechanism dominated by doping (impurity atoms) or ionised atom present (0K - 50K)
- At high temperature the phonon scattering is dominated.

For metals:

$$\sigma \propto T^{-1} \quad T > \Theta_0$$

$$\sigma \propto T^{-5} \quad T < \Theta_0$$

$$\sigma = \sigma_0 + f(T)$$



Mobility of a charge carrier is defined as the average drift

velocity per unit electric field.

$$H = V - \frac{E}{n}$$

$$M_e = \frac{V_e}{E}, \quad M_h = \frac{V_h}{E}$$

$$\text{Total mobility} \quad M_e + M_h = \frac{V_e}{E} + \frac{V_h}{E}$$

$$\text{conductivity (electron)} \quad \sigma_e = \frac{j_e}{E} = n e v_e - n e M_e \quad (3)$$

$$\text{holes} \quad \sigma_h = n h M_h \quad (4)$$

$$\text{Total conductivity} \quad \sigma_e + \sigma_h = n e (M_e + M_h)$$

① The phonon scattering (high temp.)

② Ionised impurity atoms (low temp.)

At high temp. phonon mobility

$$\text{phonon mobility} \Rightarrow \mu_p \propto T^{-3/2} \quad - (6)$$

$$\mu_i \propto T^{3/2}$$

$$\text{Ionised mobility} \Rightarrow \mu_i = B T^{3/2} \quad - (7)$$

Total resistivity

$$\rho = \rho_p + \rho_i$$

$$\frac{1}{\sigma} = \frac{1}{\sigma_p} + \frac{1}{\sigma_i}$$

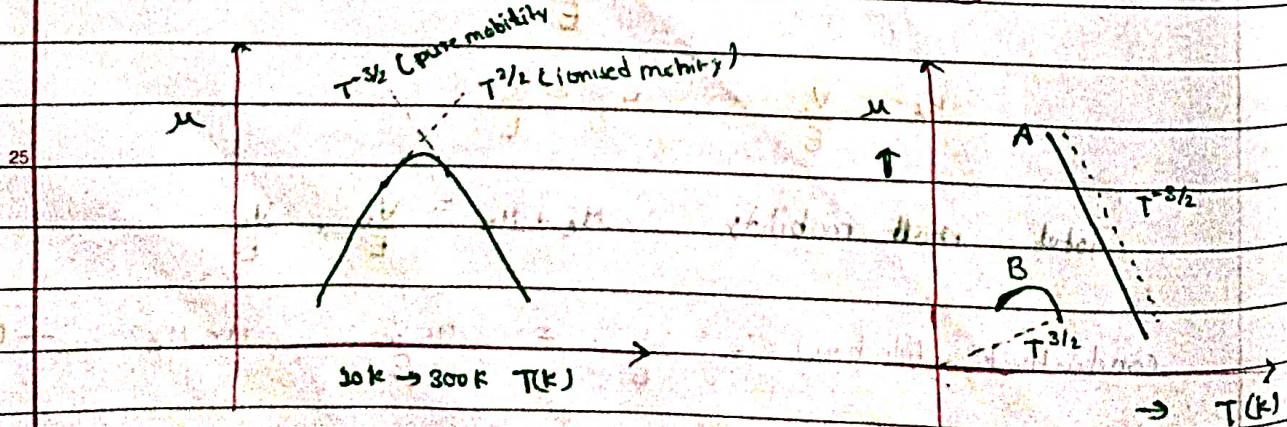
$$\frac{1}{\sigma_e} = \frac{1}{\sigma_p} + \frac{1}{\sigma_i}$$

$$\frac{1}{\mu} = \frac{1}{\mu_p} + \frac{1}{\mu_i}$$

$$\frac{1}{\mu} = \frac{T^{3/2}}{A} + \frac{T^{-3/2}}{B}$$

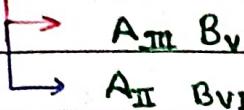
$$\mu \propto T^{3/2} \quad - (B)$$

$$\mu \propto T^{-3/2} \quad - (A')$$



## Compound Semiconductor

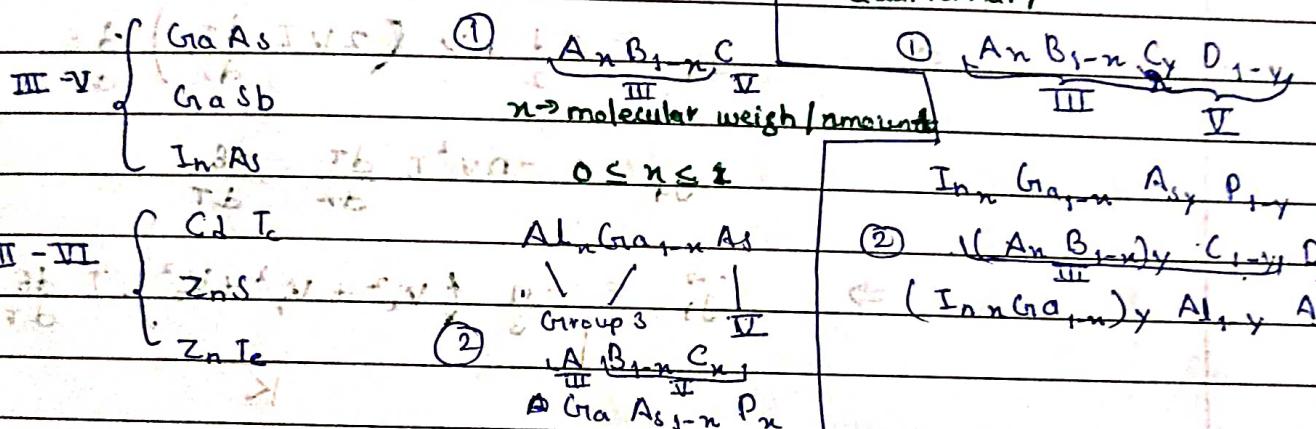
Metallic Grade Silicon (MSi)  $\rightarrow$  impure  
Electron Grade Silicon (ESi)  $\rightarrow$  pure



Binary

Ternary

Quaternary



22-8-22

Heat flow  $\rightarrow \vec{J}_q = -K \nabla T$

$$j_q = \frac{1}{2} nv [\epsilon [T(n-v)] - \epsilon [T(n-v)]]$$

Taylor Expansion:

$$\epsilon [T(n-v)] = \epsilon (T(n) - vT \frac{dT}{dn} + \dots)$$

$$\epsilon [T(n) - vT \frac{dT}{dn} + \dots] = \epsilon (T(n)) \cdot (vT \frac{dT}{dn}) \frac{d\epsilon}{dT}$$

$$\Rightarrow j_q = -\frac{1}{2} nv (2vT \frac{dT}{dn}) \frac{d\epsilon}{dT}$$

$$j_q = -nv^2 T \frac{dT}{dn} \frac{d\epsilon}{dT}$$

$$\Rightarrow j_q = -n \left( v_x^2 + v_y^2 + v_z^2 \right) T \frac{d\epsilon}{dT} \vec{\nabla} T$$

$$K = \frac{n}{3} \frac{v^2 T d\epsilon}{dT}$$

$$\Rightarrow \frac{n d\epsilon}{dT} = \frac{N}{V} \frac{d\epsilon}{dT}$$

$$\frac{1}{V} \frac{dV\epsilon}{dT} = C_V$$

$$K = \frac{1}{3} v^2 T C_V$$

$$K = \frac{1}{3} v^2 T C_V$$

$$\sigma = \frac{ne^2 T}{m}$$

$$\frac{K}{\sigma} = \frac{\frac{1}{3} C_V \cdot mv^2}{ne^2}$$

100 times higher

100 times lower

$\frac{1}{2}mv^2 = \frac{3}{2}k_B T$  ]  $\rightarrow$  Wrong but considered because

$$\Rightarrow E = \frac{3}{2}n k_B T$$

~~$C_V = \frac{dE}{dT} \Big|_V = \frac{3}{2}n k_B T$~~

$$\frac{K}{\sigma} = \frac{3}{2} \left( \frac{k_B}{e} \right)^2 T$$

9-09-2029

P-N Junctions are made by

1&gt; Diffusion

2&gt; Ion implantation

P-N Junction Diode

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Particle

diffusion current

Hole

Hole out

Electron

diff.

Electron

diff.

P

N

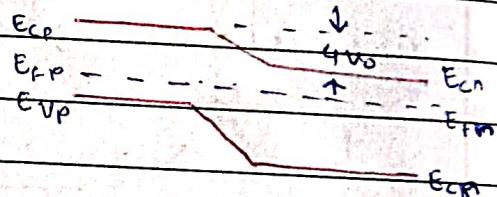
For equili:

$$J_p(\text{drift}) + J_p(\text{diff}) = 0$$

$$J_n(\text{drift}) + J_n(\text{diff}) = 0$$

$$\epsilon_{cn} = -\frac{dv}{dn}(n)$$

$$V_d = V_n - V_p$$



20

$$J_p(n) = q \left[ \mu_p p(n) \epsilon_{cn} - D_p \frac{dp(n)}{dn} \right] = 0 \quad (4)$$

[coeff. off diff.]

$$\frac{\mu_p}{D_p} \epsilon_{cn} = \frac{1}{p(n)} \cdot \frac{dp(n)}{dn} \quad (5)$$

25

$$-\frac{q}{kT} \epsilon_{cn} = \frac{1}{p(n)} \cdot \frac{dp(n)}{dn} \quad (6)$$

$$\frac{\mu_p}{D_p} = \frac{kT}{q}$$

$$-\frac{q}{kT} \int_{V_p}^{V_n} dv = \int_{p_0}^p \frac{1}{p} dp$$

30

V<sub>d</sub> contact potential

$$-\frac{q}{kT} (V_n - V_p) = \ln p_n - \ln p_0$$

$$-\frac{q}{kT} V_d = \ln \frac{p_n}{p_0}$$

$$V_0 = \frac{kT}{q} \ln \frac{P_p}{P_m}$$

$\text{Na acceptor } / \text{cm}^3 \rightarrow \text{p type side}$

$N_d$  donor /  $\text{cm}^{-3}$   $\rightarrow$  n type side

$$n_i^2 = N_a N_d$$

intrinsic carrier concentration

$$W_0 = \frac{kT}{q} \ln \frac{n_a}{n_i^2} \times n_d$$

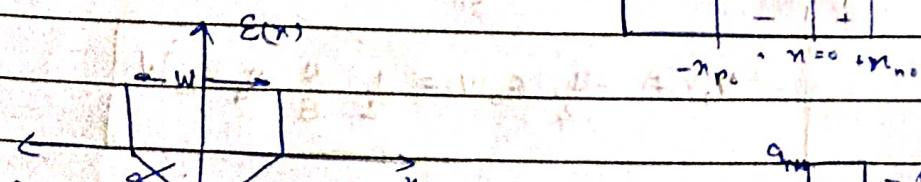
$$V_0 = \frac{kT}{4} \ln \frac{N_a N_b}{n_i^2}$$

$$\frac{P_p}{P} = e^{\frac{qV_0}{kT}}$$

$$\frac{P_p}{P_n} - \frac{n_n}{n_p} = e$$

$$Q_+ = q \propto x_n N_d$$

$$0 = q A x_{p_0} N_A$$



$$\frac{\partial E_{kin}}{\partial n} = \frac{\alpha}{E} (-qN_0) \quad \text{and} \quad \frac{\partial E_{kin}}{\partial n} = \frac{1}{G} (qN_0)$$

$$\begin{array}{c}
 q_{in} \\
 \hline
 -n_{P_2} & (+) & Q_+ = q A x_{h_0} N_d \\
 \hline
 (-) & n_{n_0} \\
 \hline
 \end{array}$$

$\downarrow$

$$Q_- = -q A x_{n_0} N_A$$

A total uncompensated charge -

$$q_A n_{p_0} N_a = q_A k_{N_a} \phi N_a$$

passion's equation -

$$\frac{dE(n)}{dn} = \frac{q}{\epsilon} (p - n + N_d^+ - N_a^-)$$

$$\frac{dE}{dn} = \frac{q}{\epsilon} N_a \quad \left. \begin{array}{l} 0 < n < n_{p0} \\ \end{array} \right\}$$

$$\frac{dE}{dn} = -\frac{q}{\epsilon} N_a \quad \left. \begin{array}{l} -n_{p0} < n < 0 \\ \end{array} \right\}$$

5-09-22 E

$$\int_0^0 \frac{dE}{dn} = \frac{q}{\epsilon} N_a \int_0^{n_{p0}} dn \quad \left. \begin{array}{l} 0 < n < n_{p0} \\ \end{array} \right\}$$

$$\int_0^0 \frac{dE}{dn} = -\frac{q}{\epsilon} N_a \int_{-n_{p0}}^0 dn \quad \left. \begin{array}{l} -n_{p0} < n < 0 \\ \end{array} \right\}$$

$$E_0 = -\frac{q}{\epsilon} N_a X_{p0} = -\frac{q}{\epsilon} N_a X_{p0} \quad \text{--- } \cancel{*}$$

$$E(n) = -\frac{q}{\epsilon} V(n)$$

$$-V_0 = \int_{-n_{p0}}^{n_{p0}} E(n) dn$$

$$V_0 = -\frac{1}{2} E_0 W = \frac{1}{2} \frac{q}{\epsilon} N_a X_{p0} W$$

$$X_{p0} N_a = n_{p0} N_a$$

$$X_{p0} = \frac{n_{p0} N_a}{N_d}$$

$$W = n_{p0} + n_{p0}$$

$$n_{p0} = \frac{W N_a}{N_a + N_d}$$

$$\frac{kT}{q} = 26 \text{ meV}$$

At room temperature

$$W = \frac{W_{p0} N_d}{N_d + N_a}$$

$$x_{p0} = \frac{WN_d}{N_a + N_d}$$

$$V_0 = \frac{1}{2} \frac{q}{G} \frac{N_a N_d}{N_a + N_d} W^2$$

$$W = \left[ \frac{2eV_0}{q} \left( \frac{N_a + N_d}{N_a N_d} \right) \right]^{1/2}$$

$$W = \left[ \frac{2eKT}{q^2} \ln \frac{N_a N_d}{N_a^2} \left( \frac{1}{N_a} + \frac{1}{N_d} \right) \right]^{1/2}$$

$$\text{as, } V_0 = \frac{KT}{q} \ln \frac{N_a N_d}{N_a^2}$$

$$x_{p0} = \frac{WN_d}{N_a + N_d} = W \left( 1 + \frac{N_a}{N_d} \right)$$

$$x_{p0} = \left[ \frac{2eV_0}{q} \left[ \frac{N_d}{N_a(N_a + N_d)} \right] \right]^{1/2}$$

$$x_{n0} = \left[ \frac{2eV_0}{q} \left[ \frac{N_a}{N_a(N_a + N_d)} \right] \right]^{1/2}$$

- (Q) ~~phosphorous~~  
Boron is implemented into the n-type side Boron is implemented q into silicon sample forming a junction

$$N_d = 10^{16} \text{ cm}^{-3}, A = 2 \times 10^{-3} \text{ cm}^2, N_i = 1.5 \times 10^{16} \text{ cm}^{-3}$$

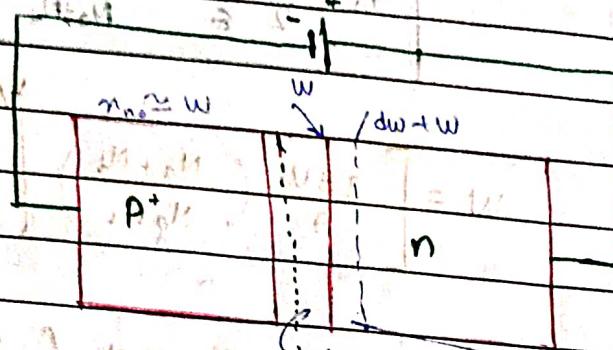
- Assume that the acceptor cont concentration in p-type region is  $N_a = 4 \times 10^{28} \text{ cm}^{-3}$ . Calculate the  $V_0$ ,  $x_{n0}$ ,  $x_{p0}$

$$e = 1.6 \times 10^{-19} \quad (Q) V_0 = \frac{kT}{q} \ln \frac{N_a N_d}{N_a^2}, W = \sqrt{\frac{2eKT}{q^2} \left( \frac{N_a + N_d}{N_a N_d} \right)}$$

$$x_{p0} = \frac{WN_d}{N_a + N_d}, \quad x_{n0} = \frac{WN_a}{N_a + N_d}$$

## Capacitance in p-N junction diode :-

- (1) The junction capacitance → Reverse bias
- (2) The charge storage capacitance → Forward bias



$$Q = qAN_d w \quad C = \frac{dQ}{dV} \Rightarrow C = \frac{d}{dV} \left( \frac{qAN_d w}{\epsilon_0} \right)$$

$$w = \sqrt{\frac{2\epsilon_0 (V_0 - V)}{qN_d}}$$

$$w = \sqrt{\frac{2\epsilon_0 (V_0 - V)}{q(N_p + N_d)}} \quad \rightarrow \text{with bias}$$

$$|Q| = qAN_d w = qA\pi_{pn} N_d$$

$$N_{pn} = N_p w + N_d w = \frac{N_p w}{N_p + N_d}$$

$$|Q| = qA\pi_{pn} N_d w$$

$$C = \frac{dQ}{dV} = A \left[ \frac{2q\epsilon_0 (V_0 - V)}{N_p + N_d} \right]^{1/2}$$

$$C = \frac{dQ}{dV}$$

$$C_J = \frac{dQ}{d(V_0 - V)}$$

$$C_j = \frac{\epsilon^2}{2} A \left[ \frac{N_a N_d}{(N_a + N_d)} \right]^{1/2}$$

$$C_j \propto (V_0 - V)^{1/2}$$

$$C_j = \frac{\epsilon^2}{w} A \quad [\text{parallel plate capacitor}]$$

$p^+$  - n junction

$$\rightarrow N_a \gg N_d$$

$$N_a \approx w$$

$$C_j = \frac{A}{2} \left[ \frac{2\epsilon N_a}{V_0 - V} \right]^{1/2}$$

$$C_j^2 = \frac{A^3}{4} \left[ \frac{2\epsilon N_a}{V_0 - V} \right]$$

$$\frac{1}{C_j^2}$$

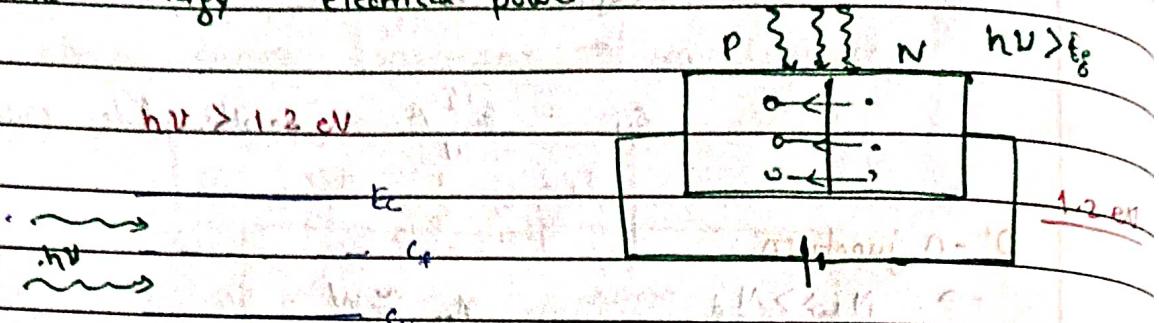
$$\text{slope} = \frac{2}{C_j \epsilon N_a}$$

$$-V_{bi} \quad V_A \rightarrow$$

- Q. Find out the impurity doping concentration in a  $p^+$  - n junction at 300 K. The intrinsic  $n_i = 1.5 \times 10^{10} / \text{cm}^3$

$$V_{bi} = 0.855 \text{ V}, \text{ slope} = 1.32 \times 10^{-1} \text{ F/cm}^2 (\text{volt})$$

16 - 09 - 22

Solar cellP-N  $\rightarrow$  Junction diodePhoton energy  $\rightarrow$  Electrical power

$$h\nu > E_c + E_v = E_g$$

$G_i \rightarrow$  rate of generation

$L_h \rightarrow$  Diffusion length of holes into n-type side

$L_e \rightarrow$  Diffusion length of electron into the p-type side

$$A L_h \times G_i \times q$$

$$A L_e \times G_i \times q$$

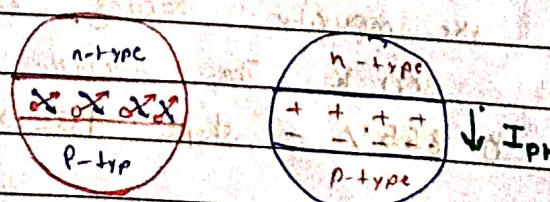
$$\text{photo current} = A L_h \cdot G_i \cdot q + A L_e \cdot G_i \cdot q$$

$$= A (G_i (L_h + L_e)) \quad - (1)$$

$$I = I_s (e^{\frac{qV}{kT}} - 1) \quad - (2)$$

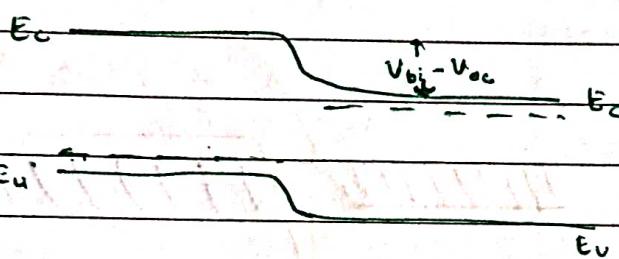
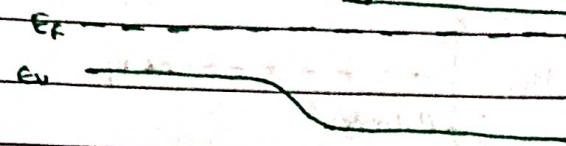
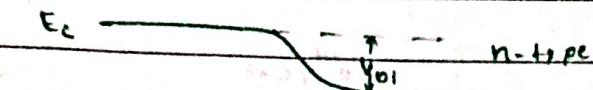
$$I = q A \left[ \frac{L_h p_{n0}}{T_h} + \frac{L_e N_{p0}}{T_e} \right] (e^{\frac{qV}{kT}} - 1) \quad - (2)$$

Direction of photocurrent



$$I = I_s (e^{\frac{qV}{kT}} - 1) - I_{ph}$$

## Energy band diagram.



$$I = I_s \left( e^{\frac{qU}{kT}} - 1 \right) - I_{ph}$$

The short circuit current

$$V=0$$

$$I_{sc} = -I_{ph} = -q A v_n (L_n + L_e)$$

Open circuit voltage  $\rightarrow I = 0$

$$V = V_{oc} = \frac{k_B T}{q} \ln \left( \frac{I_{ph}}{I_s} + 1 \right)$$

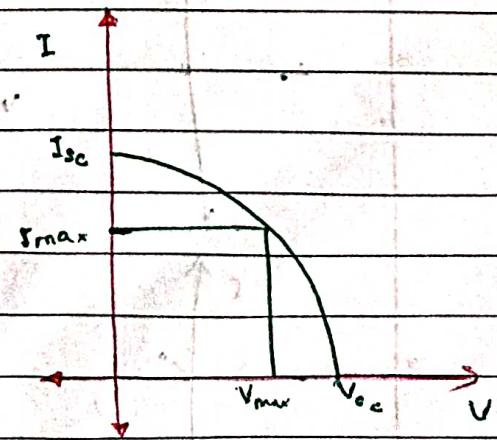
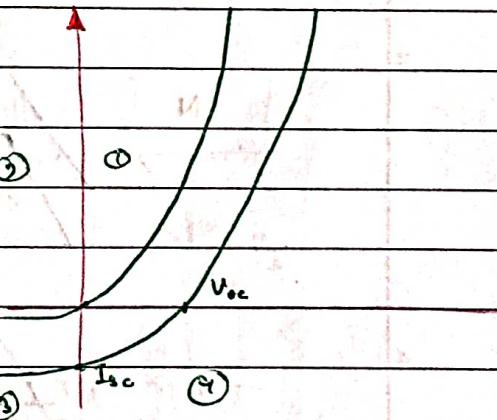
$$V_{oc} = \frac{k_B T}{q} \ln \left( \frac{I_{ph}}{I_s} \right)$$

$$P_{out\ max} = V_{max} \times I_{max}$$

$$F.F.V = \frac{P_{max}}{I_{sc} \times V_{oc}}$$

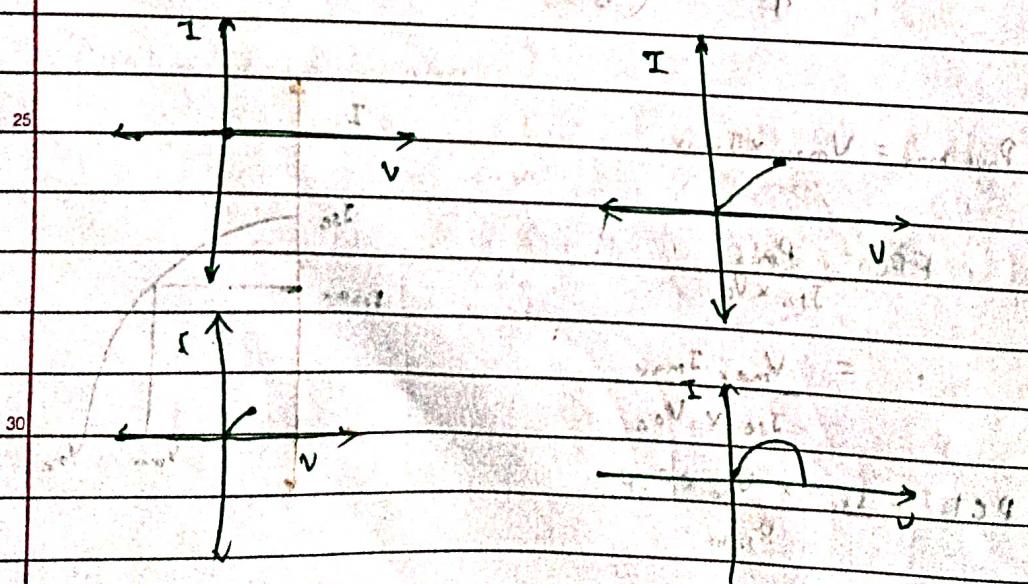
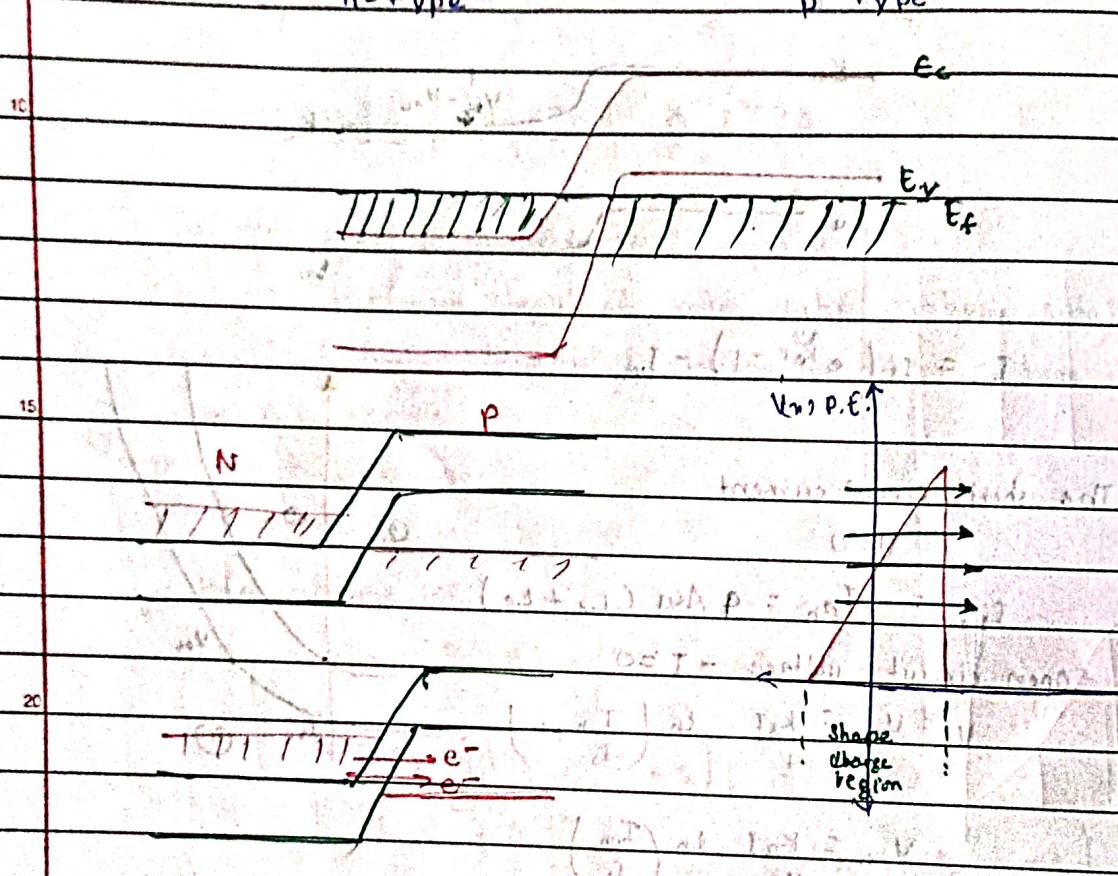
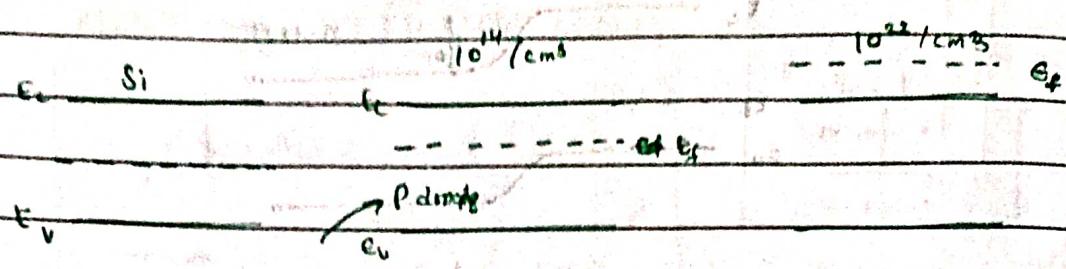
$$= \frac{V_{max} I_{max}}{I_{sc} \times V_{oc}}$$

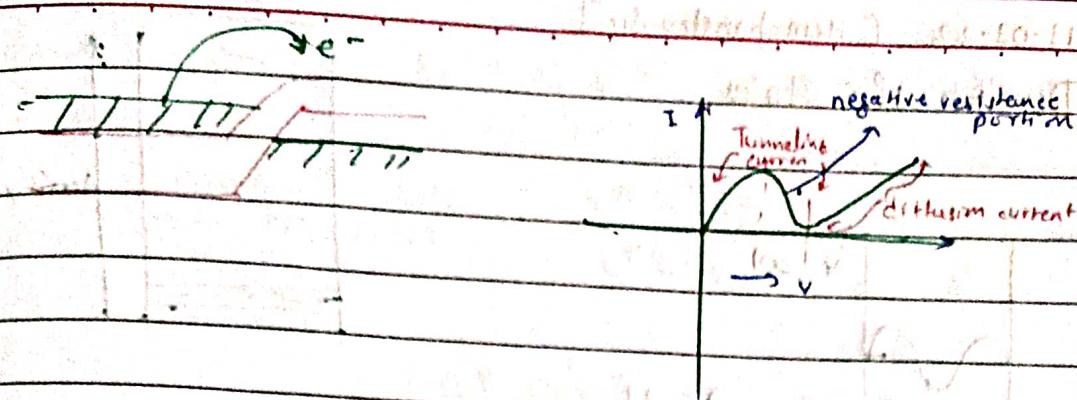
$$P_{CB} = I_{sc} \times V_{oc} \times F.F. \cdot P_{light}$$



## \* Tunnel Diode

Thickness is not thin, that the electron can go through it.





- Negative resistance portion  $\rightarrow$  due to increase in voltage, current decreasing
- This shows diode is oscillating

13/10/22

## \* Semiconductor Device fabrication crystal growth and wafer preparation

silicon in form of crystalline

We need 'clean room' / 'clean environment'

Types of room { 100000 → order clean room

10000 → .. " " 200

.. 100 → .. " " "

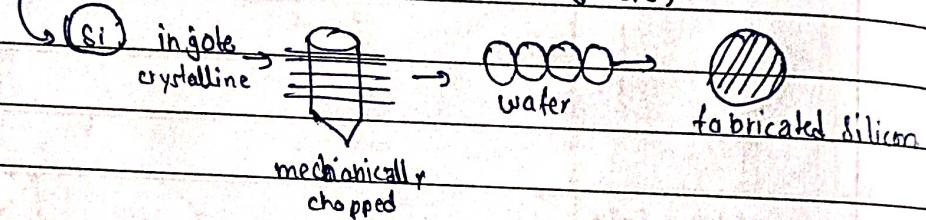
10 (Best) .. " " 1000

required

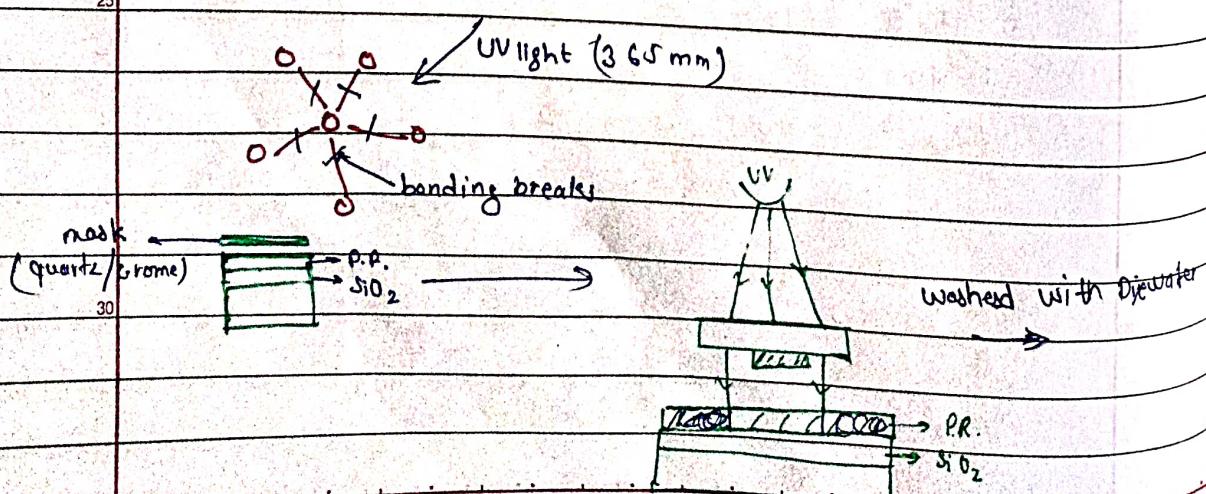
Si → Metallurgical grade silicon (MGS)

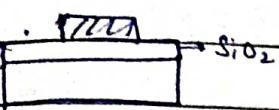
Purification ↓ (bur)

Si → Electronic Grade silicon (EGS)



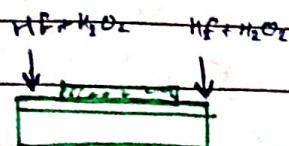
lithography → photosensitive chemical





Cohsil unitime 1997 031

Etching → Reactive ion Etching

→ chemical etching ( $\text{HF} + \text{N}_2\text{O}_2 + \text{H}_2\text{O}$ )

Metallization

Thermal / e-beam evaporation

Process simulation

P&amp;VLSI Process Integration

Packaging

Yield &amp; Reliability

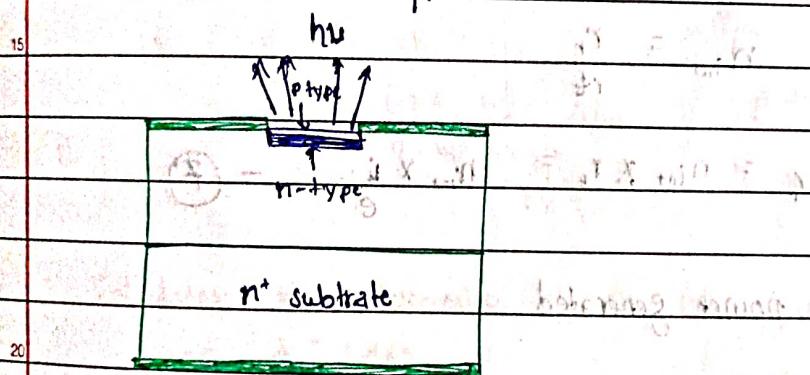
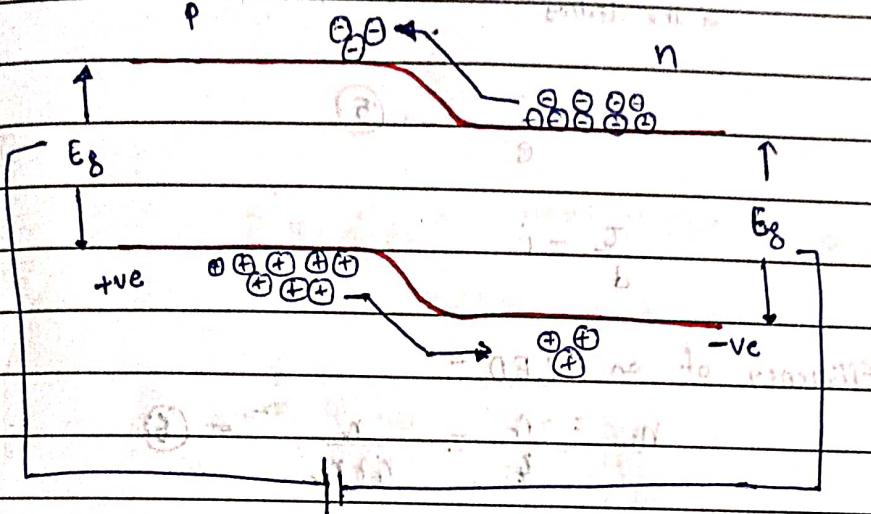
Marketing

20/10/12

## Basic classification

Homojunction

Heterojunction (DH)

 LED  $\rightarrow$  forward bias.


$$\Delta n = \Delta n(0) \exp(-t/\tau)$$

↑  
no. of minority  
present in p type side

 current at junction density  $= j \text{ A/m}^2$ 

$j$   $\rightarrow$  is the electron flow per unit area per second  $\text{m}^2/\text{s}$

$$\frac{d(\Delta n)}{dt} = \frac{j}{e d} - \frac{\Delta n}{\tau} (\text{m}^{-1}\text{s}^{-1})$$

$$\frac{d(\Delta n)}{dt} = 0$$

Radiative recombination  
Non Radiative recombination

scribbles

absorbed current

$$\Delta n = \frac{J}{e d} \text{ m}^{-3} \quad - (2)$$

(NRA) recombination

diffusion current

$$r_p = \frac{J}{e d} \quad - (3)$$

Total recombination  
of the electron

$$r_t = r_p + r_{nr} \quad - (4)$$

$$r_t = \frac{i}{e} \quad - (5)$$

$$\frac{I}{d} = i$$

Efficiency of an LED -

$$n_{int} = \frac{r_p}{r_t} = \frac{r_p}{r_p + r_{nr}} \quad - (6)$$

$$n_{int} = \frac{r_p}{r_t}$$

$$r_p = n_{int} \times r_t = n_{int} \times \frac{i}{e} \quad - (7)$$

internal power generated

$$P_{int} = n_{int} \times i \times h f$$

$$P_{int} = n_{int} \times \frac{h e i}{c \lambda}$$

$$n_{int} = \frac{1}{1 + \frac{r_{nr}}{r_p}}$$

$$T_p = \frac{\Delta n}{r_p}, \quad T_{nr} = \frac{\Delta n}{r_{nr}}$$

$$\text{Loss} \cdot \Delta R \cdot n_{\text{min}}^2 = 0.122 \quad \text{non-radiative recombination}$$

$1 + \frac{T_e}{T_{\text{rec}}} \quad T_{\text{rec}}$

is known as

$$\frac{1}{T_e} = \frac{1}{T_s} + \frac{1}{T_{\text{rec}}}$$

$$n_{\text{min}} = \frac{T_e}{T_{\text{rec}}}$$

$$R = \frac{\Phi \cdot h\nu}{I} \quad \begin{array}{l} \text{flux} \\ \text{energy of photon} \\ \text{Total current of the device} \end{array}$$

$$= \frac{\Phi \cdot h\nu}{P_{\text{eq}}} = n_0 \frac{h\nu}{q}$$

$$R = \frac{1.24 h_0 A/w}{\lambda (\mu\text{m})} \quad P = n_0 I \times \frac{h\nu}{q}$$

Q) Calculate the responsive net of LED given that  $h_0 = 3.1$   
and  $\lambda = 1.4\text{ }\mu\text{m}$

$$R = 1.24 \times 0.03$$

Q- Calculate the output power for an  $n^+ - p$  of  $\text{GaAs}$   
LED with electron current of  $1.0 \text{ mA}$  and efficiency  
 $n_0 = 50^{-1}$ .

$$A_{\text{in}} = 0.7 \text{ mW}$$

Radiative and non-radiative recombination of an minority carrier in active region of an LED are  $60 \text{ ns}$  and  $100 \text{ ns}$  respectively.

- Determine the total carrier recombination lifetime.
- Power internally generated within the device when the peak generation

emission wavelength is 0.87 μA. and device current is 40 mA.

5

10

15

20

A. i)

25

Hg P.D.A

B. i)

20

Hg P.D.A

ii)

25

Hg P.D.A

iii)

25

Hg P.D.A

iv)

25

Hg P.D.A

v)

25

Hg P.D.A

vi)

25

Hg P.D.A

vii)

25

Hg P.D.A

viii)

25

Hg P.D.A

ix)

25

Hg P.D.A

x)

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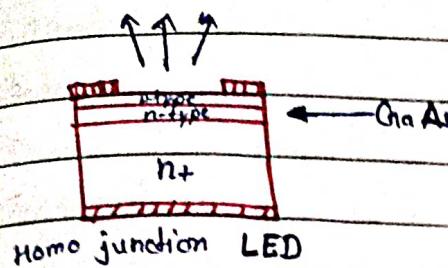
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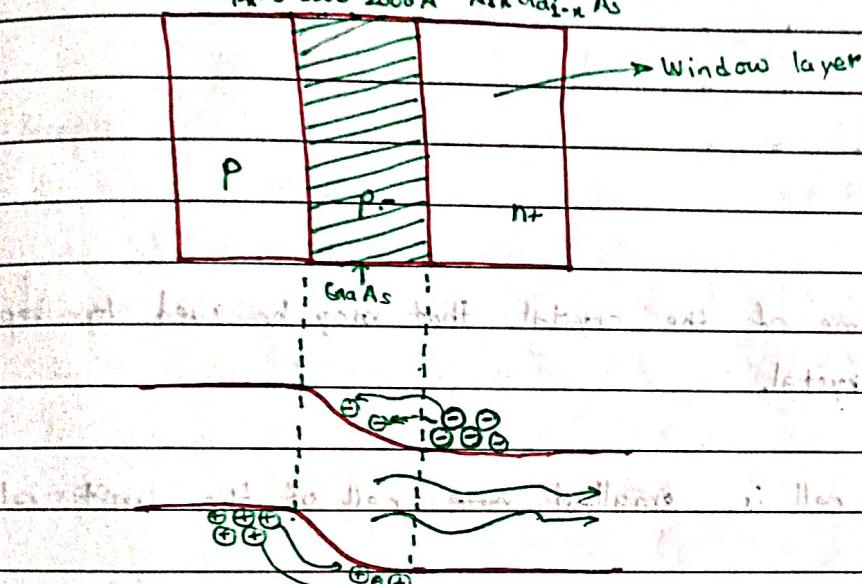
31/10/22 [Aniruddha Sir]



① The absorption of photon in the p-type side (low)

②

Heterojunction LED  $\text{Al}_x \text{Ga}_{1-x} \text{As}$   
 $\text{Al}_x \text{Ga}_{1-x} \text{As} 1000-2000\text{\AA}$   $\text{Al}_y \text{Ga}_{1-y} \text{As}$



Q = Definitions of the radiative and non radiative combinations

Q - The problems find out in homojunction and its removal with introduction of homogeneous led.

Q -

## Crystal Structure

Amorphous →



Polycrystalline →



Crystalline →



### Lattice

↑  
arrangement  
of atoms

lattice point

### Unit cell

A small volume of the crystal that may be used to reproduce the entire crystal.

### Primitive cell

The primitive cell is smallest one cell of the unit cell

### Basis

No. of atoms like diatomic ( $\text{NaCl}$ ), triatomic.

Basis + lattice = crystal

### Crystal structure

- ① Simple
- ② Body centered cubic (BCC)
- ③ FCC

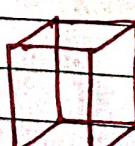


Nature of unit cell :  $a = b = c$ ,  $\alpha = \beta = \gamma = 90^\circ$

### Tetragonal

- ① Simple
- ② Body centered

} ②



$a = b \neq c$   
 $\alpha = \beta = \gamma = 90^\circ$

- Trigonal**
- ① Simple
  - ② Body
  - ③ Face
  - ④ Hexagonal

 $\alpha \neq \beta \neq \gamma$ Monoclinic system  $\alpha = \beta = 90^\circ$ 

- Monoclinic**
- ⑤ Simple
  - ⑥ Body

 $\alpha \neq \beta \neq \gamma$  $\alpha = \beta = 90^\circ \neq \gamma$ 

- Triclinic**
- ⑦ Simple

 $\alpha \neq \beta \neq \gamma$  $\alpha \neq \beta \neq \gamma \neq 90^\circ$ 

- Trigonal**
- ⑧ Simple

 $a = b = c$  $\alpha \neq \beta \neq \gamma \neq 90^\circ$ 

- Hexagonal**
- ⑨ simple

 $a = b \neq c$  $\alpha = \beta = 90^\circ, \gamma = 120^\circ$ 

## Packing efficiency



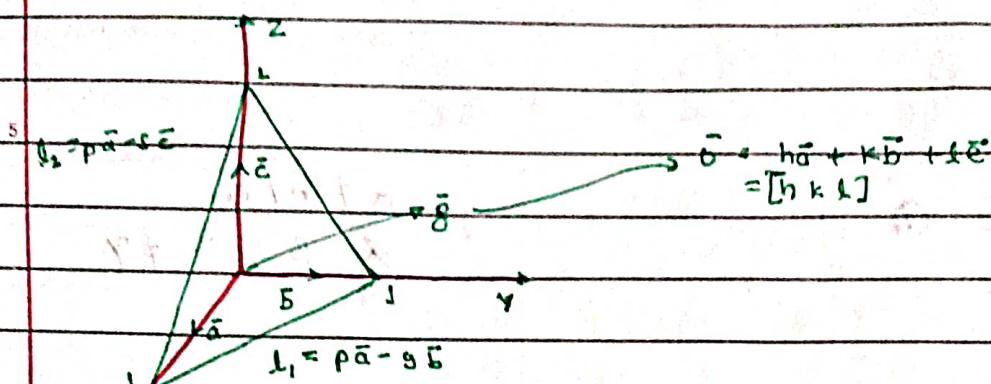
$$\text{P.E.} = \frac{\frac{4}{3}\pi r^3}{\frac{8r^3}{G}} = \frac{\pi}{6} = 3.14$$

$$= 0.523$$

$$\text{P.E. \%} = 52.3\%$$

03/11/22 [DNM]

## Crystal plane and Miller indices



### Imperfection of solids (crystals)

- 1) Thermal vibrations → point defects
  - Schottky defects
  - Frankel defects
- 2) Compositional defects
  - Computational defects
  - Substitutional Defects
  - Interstitial defects.
- 3) Line defects
  - Edge dislocation
  - Screw dislocation
- 4) Surface defects
  - Grain boundaries
  - Twin boundary
  - Tilt boundary
  - Staking fault

**Schottky defect** — In the case of schottky defect, if an atom displaces from its lattice site to the surface to make the charge neutrality, the opposite side atoms will also move from opposite side from its regular lattice position so the combinative combination of vacancies and imperfections will be created. This kind of defects can be obtained in ionic crystals where ions of both type (cation and anions) migrate to the crystal surface leaving a vacancy on both ionic sides.

and thus maintaining charge neutrality of the crystal.

**Frenkel defect :** If the charge neutrality is maintained by having a positive ion in an interstitial position the pair constitute the Frenkel defects closely related to the interstitial.

**Schottky defects :**

$n = \text{no. of vacant sites}$

$N = \text{no. of atoms}$

Probability  $P = \frac{N!}{(N-n)! n!}^2$

$$S = k_B \log P$$

$$= k_B \log \left[ \frac{N!}{(N-n)! n!} \right]^2$$

from free energy eq -

$$F = U - TS$$

$$= nE_p - TS$$

$$= nE_p - 2k_B T \log \left[ \frac{N!}{(N-n)! n!} \right]^2$$

$$= nE_p - 2k_B T \times 2 [\log N! - \log (N-n)! - \log n!]$$

$$= nE_p - 2k_B T \times 2 [n \log N - (N-n) \log (N-n) - n \log n]$$

25

30

04/11/22 [ANB]

$$F = nE_p - 2k_B T [N \log N - (N-n) \log(N-n) - n \log n]$$

$$\left(\frac{dF}{dn}\right)_T = E_p - 2k_B T \log\left(\frac{N-n}{n}\right) = 0$$

$$\frac{E_p}{2k_B T} = \log\left(\frac{N-n}{n}\right)$$

$$\frac{N-n}{n} = \exp\left(\frac{E_p}{2k_B T}\right)$$

$$n = N \exp\left(-\frac{E_p}{2k_B T}\right)$$

$$n \ll N$$

$$\frac{n}{N} = \exp\left(-\frac{E_p}{2k_B T}\right)$$

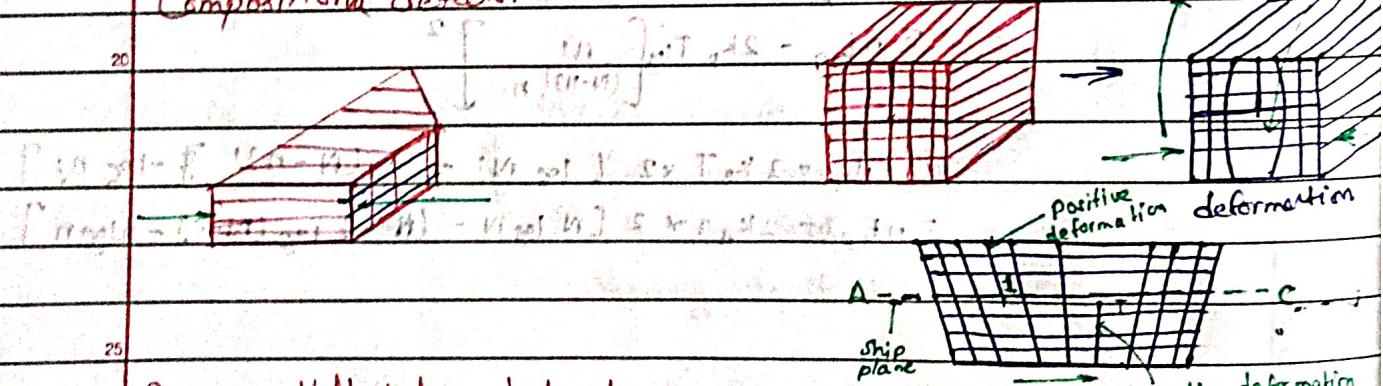
$$= \exp\left(\frac{-2.02}{0.025}\right)$$

$$= \exp(-40.4)$$

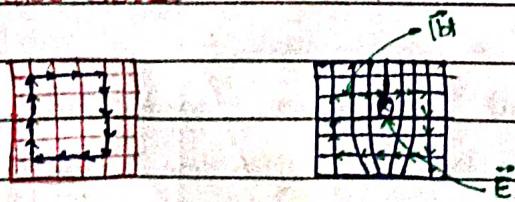
$$\frac{n}{N} = 2.8 \times 10^{-18}$$

- The magnitude of deformation
- Direction of the deformation
- Edge dislocation / plane

### Compositional defects.

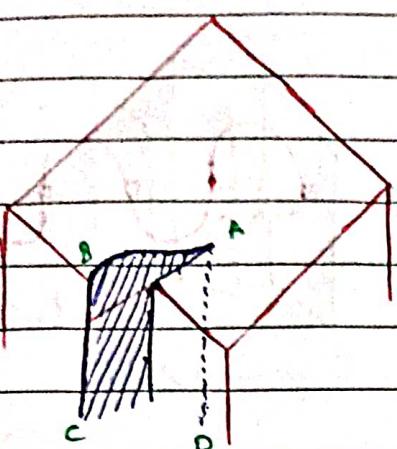
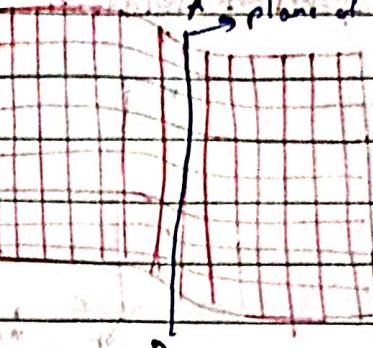


### Burger dislocation

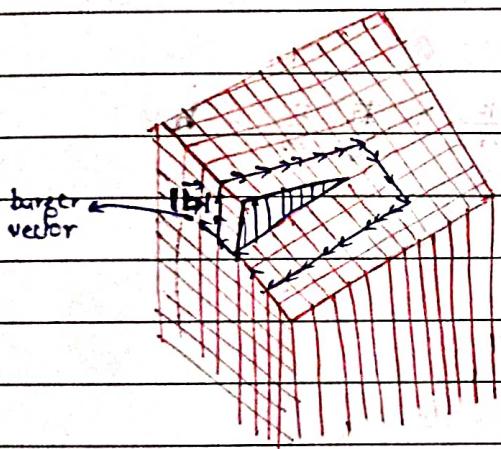


PP dislocation line

(a)  $\frac{1}{2}[111]$  dislocation



Screw dislocation  
is parallel to the  
direction the Burger vector

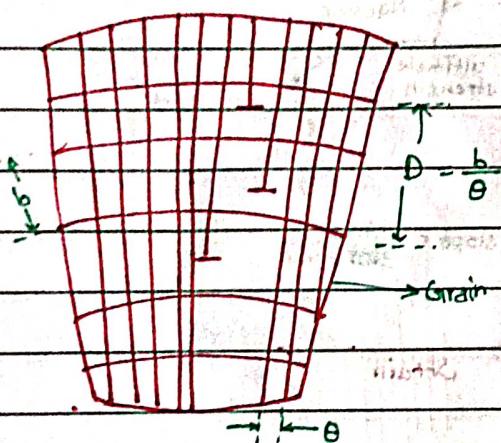


16/11/22

## Grain boundaries

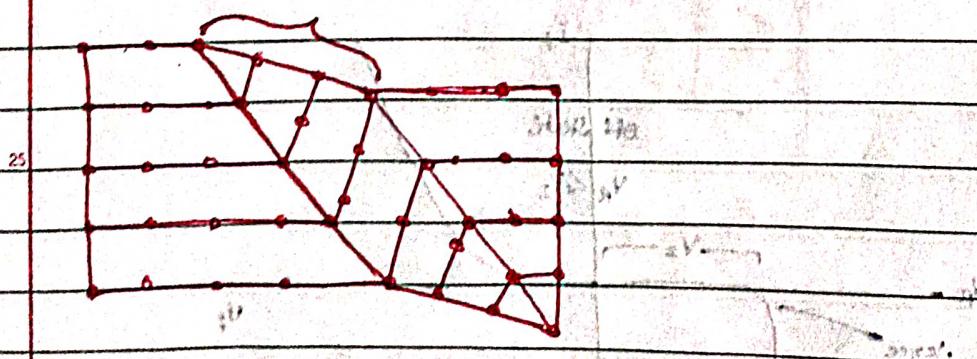
- Tilt boundaries: ( $\theta < 10^\circ$ )

The tilt boundary another surface in perfection which is known as small-angle boundary or orientation difference between two neighbouring crystals less than  $10^\circ$ . The low angle boundary can be described by suitable arrays of dislocation.



- Twin boundaries

If the atomic arrangement on one side of a twin boundaries is a mirror reflection of the arrangement of the other side



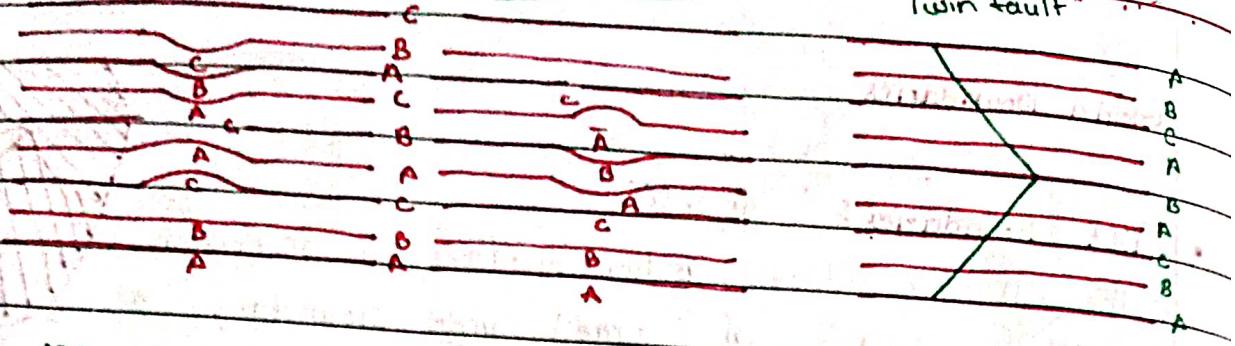
- Stacking defects

Stacking fault is a fault in surface imperfection that arises from stacking of one atomic plane out of sequence of another, while the lattice on either side of the fault is perfect.

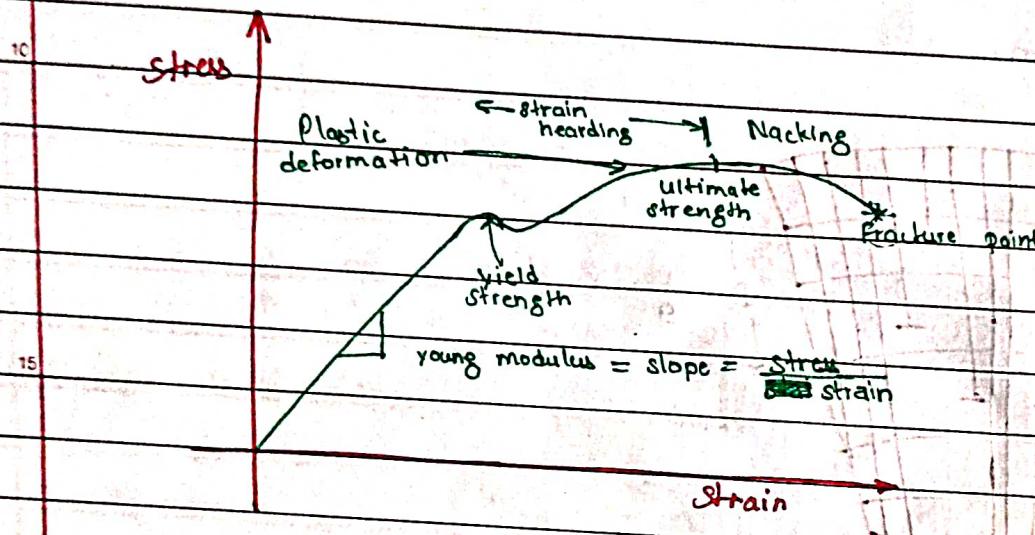
Intrinsic fault

Extrinsic fault

Twin fault



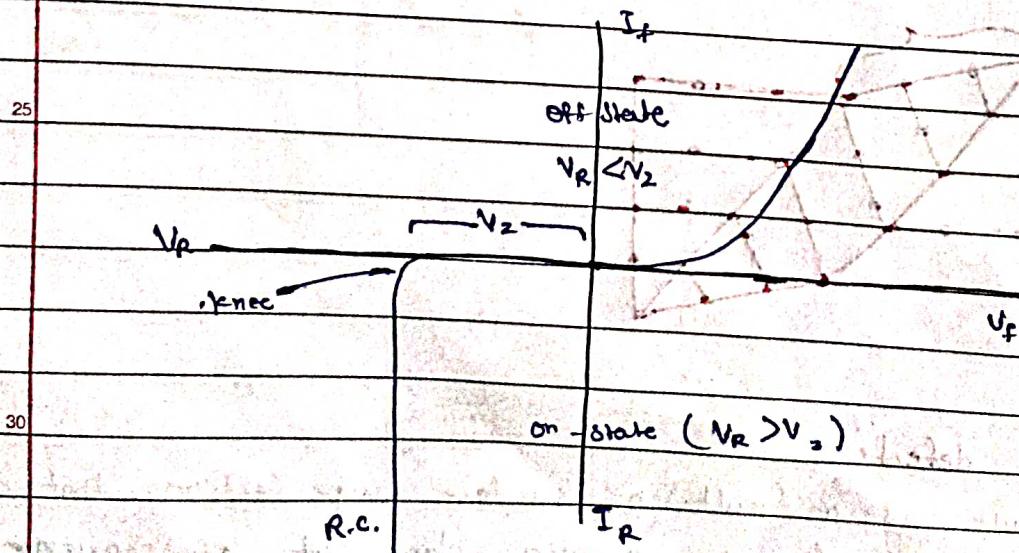
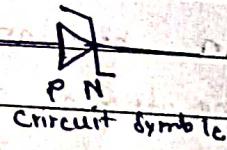
ABC AC ABC



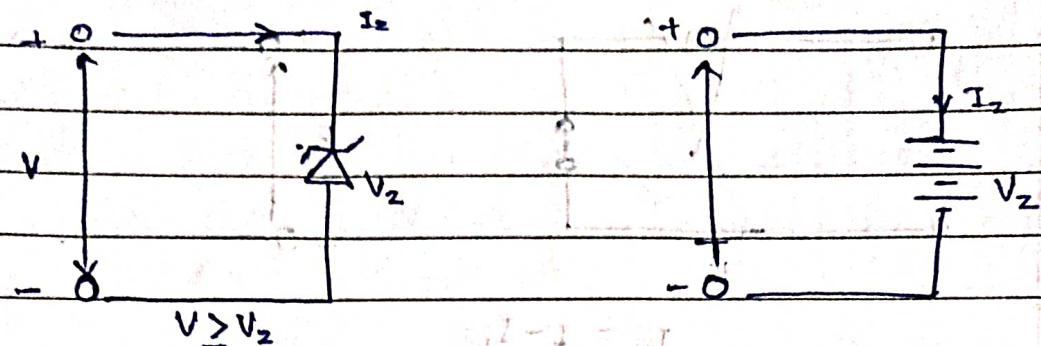
~~11/11/22~~

## Zener diode

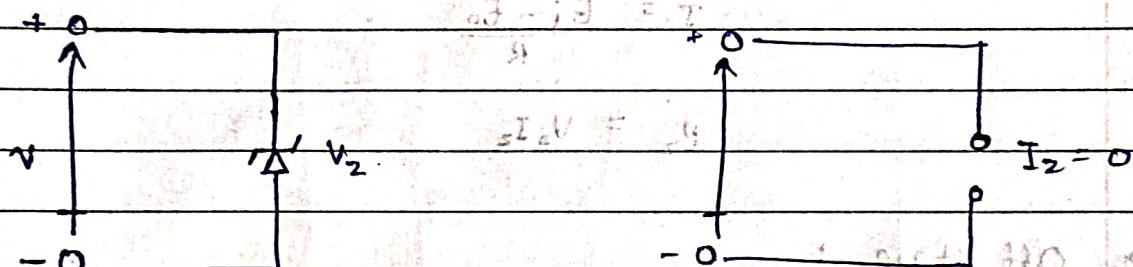
- ① Highly doped - P-N Junction
- ② The breakdown in zener breakdown



① On state :-

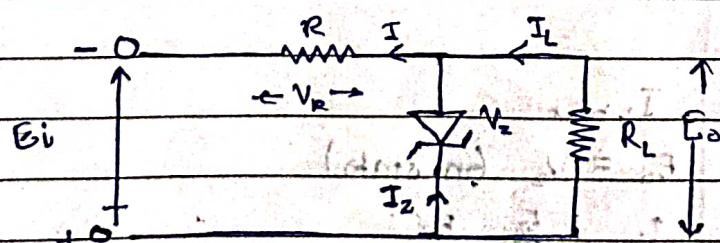


② OFF state :



Zener Diode as a voltage stabilisation

$$I_Z + I_L = I$$



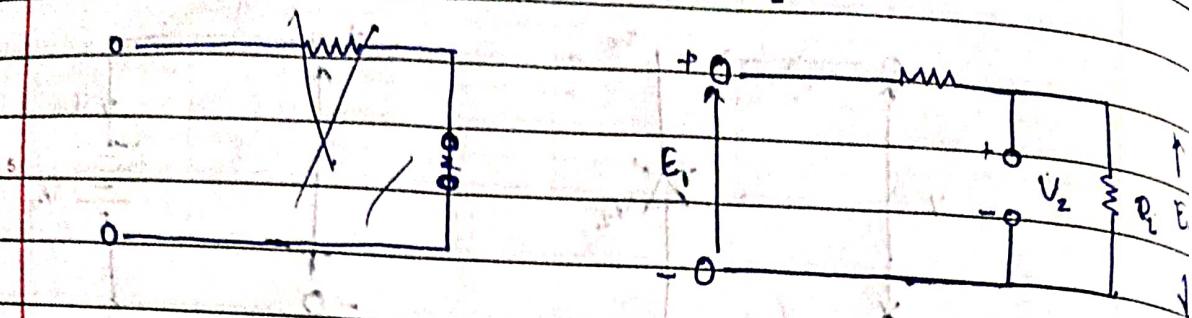
$$V_o = E_i - E_o$$

$$I = I_Z + I_L$$

$$R = \frac{E_i - E_o}{I_Z + I_L}$$

$$E_o = \frac{R_L E_i}{R + R_L}$$

①  $E_i$  and  $R_L$  fixed :  $V_2 = E_o = \frac{R_L E_i}{R + R_L}$  i) on state



$$I_2 = I - I_L$$

$$I_o = \frac{E_o}{R_L}$$

$$I = \frac{E_i - E_o}{R}$$

$$P_2 = V_2 I_2$$

ii) Off state :

$$V_2 = E_o = 0 \quad I = I_L, \quad I_2 = 0 \quad P_2 = 0$$

$$V_o = E_i - E_o, \quad V = E_o \quad (V < V_2)$$

$$P_2 = V \times I_2 = 0$$

$$I = I_L + I$$

② Fixed  $E_i$  but variable  $R_L$

①  $R_L$  min and  $I_{L\max}$

$$E_o = V_2 \text{ (on state)}$$

$$\therefore I_L = \frac{E_o}{R_L} = \frac{E_i}{R_L}$$

$$E_o = V_2 = \frac{R_L \min V_1}{R + R_L \min}$$

$$R_{L\min} = \frac{R V_2}{E_i - V_2} \rightarrow \text{on state}$$

ii)  $I_L$  min and  $R_L$  max

$$I_2 = I - I_L$$

$$I_{L\min} = I - I_{2\max}$$

$$R_{\text{max}} = \frac{E_0}{I_{L\text{min}}} = \frac{V_2}{I_{L\text{min}}}$$

③ Fixed  $R_L$  but variable  $E_i$ :

i)  $E_{i\text{ min}}$

$$E_0 = V_2$$

$$E_0 = V_2 = R_L E_i$$

$$E_{i\text{ min}} = \frac{(R+R_L) V_2}{R+R_L}$$

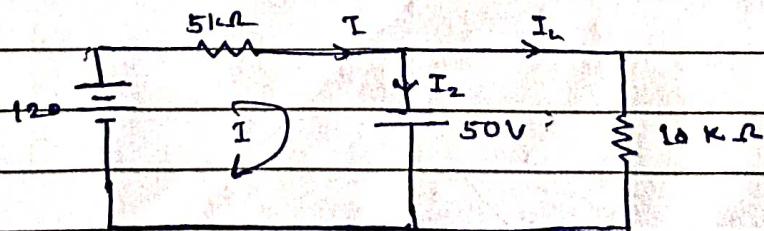
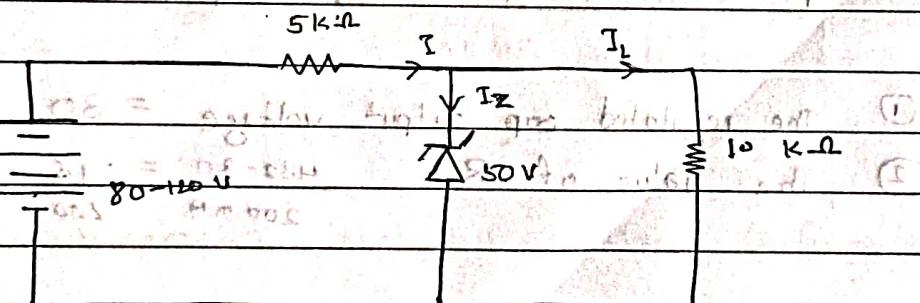
ii)  $E_{i\text{ (max)}}$

$$I = I_2 + I_L$$

$$\therefore I_{\text{max}} = I_{2\text{ max}} + I_L$$

$$E_{i\text{ (max)}} = I_{\text{max}} R + V_2$$

Q -



$$I_{L\text{ (max)}} = 9 \text{ mA}$$

$$I_{2\text{ min}} = 1 \text{ mA}$$

$$-5 \times 10^3 I + 50 + 120 = 0$$

$$1. = -120 \rightarrow I = 34 \text{ mA}$$

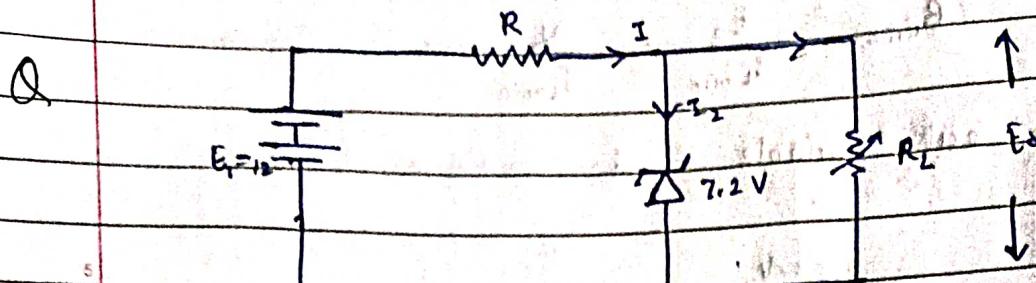
$$-10 I_L \times 10^3 - 50 = 0$$

$$I_L = \frac{50}{10} \rightarrow I_L = 5 \text{ mA}$$

$$120 = I_T \times 5 \times 10^3 + 50$$

$$I_2 = I - I_L = 29 \text{ mA}$$

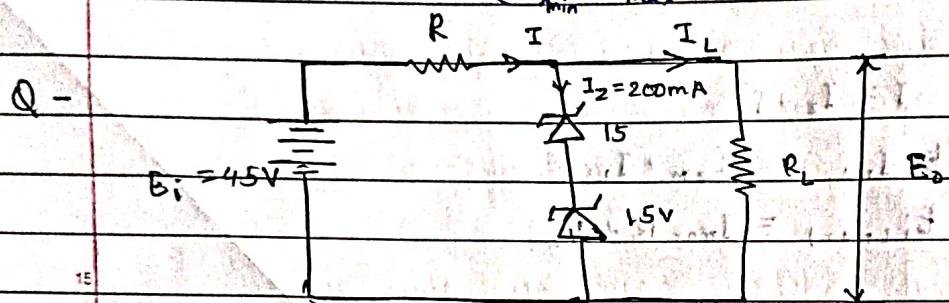
$$\frac{20}{5} = 2 \text{ mA}$$



$$I_{2 \text{ min}} = 10 \text{ mA}$$

$$I_2 \neq 32 \text{ to } 100 \text{ mA}$$

$$R = \frac{E_i - E_o}{(I_2) + (I_L)_{\text{max}}} = 48.5 \Omega$$



① The regulated output voltage = 30

② The value of  $R_L = \frac{45V - 30}{200 \text{ mA}} = 15 \text{ k}\Omega$